What is claimed is:

1. A cleaning member for use in cleaning a substrate, comprising:

a flat tip surface configured to be in contact with the substrate when cleaning the substrate, and the tip surface being not covered with a skin layer; and

a circumferential part having a covered part, which is disposed on a base end side and is covered with the skin layer, and an exposed part, which is disposed on a tip end side and is not covered with the skin layer.

2. The cleaning member according to claim 1,

wherein the exposed part has a height equal to or more than a length of compression, by which the cleaning member can be compressed at the time of compression.

3. The cleaning member according to claim 1,

wherein the exposed part has a height in the range of 1 mm to 5 mm.

4. The cleaning member according to claim 1,

wherein a base surface, which is a surface disposed on an opposite side of the tip surface is not covered with the skin layer.

5. The cleaning member according to claim 1,

wherein the cleaning member is a pencil-type cleaning member.

6. The cleaning member according to claim 1,

wherein the cleaning member is a nodule.

7. The cleaning member according to claim 1,

wherein the exposed part is tapered toward the tip end side and has a trapezoidal vertical cross section, or the exposed part is stepped decreasingly toward the tip end side and has a stepped vertical cross section.

8. A substrate cleaning apparatus comprising:

a substrate holder for holding a substrate; and

the cleaning member, according to claim 1, used to clean the substrate.

9. The cleaning member according to claim 1,

wherein a cross-sectional side view of the exposed part has a rectangle shape.

10. A pencil-type cleaning member for use in cleaning a substrate, comprising:

a sponge part,

wherein the sponge part has

a base surface being not covered with a skin layer,

a flat tip surface configured to be in contact with the substrate when cleaning the substrate and being not covered with a skin layer, and

a circumferential part having a covered part, which is disposed on a base end side of the sponge part and is covered with the skin layer, and an exposed part, which is disposed on a tip end side of the sponge part and is not covered with the skin layer.

11. A substrate processing apparatus comprising:

a housing;

a polishing unit for polishing a substrate;

the cleaning unit, according to claim 8, for cleaning the substrate after polished;

a drying unit for drying the substrate after cleaned;

a control unit for controlling the substrate processing apparatus; and

a memory unit for storing data.